

Applicant(s):

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Assignee:

WaferMasters, Inc.

COPY OF PAPERS

Title:

Wafer Transport System and Method

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BOX NON-FEE AMENDMENT

RESPONSE TO OFFICE ACTION

Dear Sir:

In response to the Office Action dated March 28, 2002, Applicants submit the following amendments and remarks.

IN THE CLAIMS

The following is a clean version of the entire set of pending claims. No Claims are amended.

A method for transporting semiconductor wafers comprising: 1. providing a processing system including a transport module and process chamber; extending a semiconductor wafer transport device from said transport module into an adjacently positioned container, said container being a separate component from said processing system; and

removing at least one semiconductor wafer from said container using said wafer transport device.

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